

Study of surface contamination on ultralow background (ULB) materials

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PNNL is operated by Battelle for the U.S. Department of Energy







HEMT SuperCDMS Tower Board 4-Kelvin SQUID Board Still Plate Cold Plate Mixing Chamber **Outer Neutron Shield** Radon /acuum Coax Barrier Graded Pb Gamma Shield Detector Detector Inner Neutron Shield Clamps Housing Vertical Flex Cable Nested NI cans E-stem C-stem Horizontal Flex Cable Shield Detect

SuperCDMS SNOLAB detector



The usual suspects

Pacific

Uranium-238



Thorium-232



Validation of all materials: a challenging task

\rightarrow Extremely stringent radiopurity requirements



Ultra sensitive analytical techniques Dedicated facilities







> Meticulously clean analytical procedure specifically developed \geq R&D to develop ultrapure materials (*i.e.*, electroformed copper)





After validation, will materials remain "ultraclean" forever?

\rightarrow Surface contamination!

- Manufacturing and processing
- > Handling for assembly
- > Machining
- Moving and storage



SCDMS detector components

Exposure to dust, even in clean rooms!



MAJORANA DEMONSTRATOR detector components









ICP-MS: a powerful tool

Direct, fast, quantitativeSurface and bulk



- > Understanding
- Identifying rather than observing (too late!)
- Quantifying and controlling



Exposure to dust: direct measurement of dust activity

Surface exposure
Surface leaching
Quantitative analysis

PFA (Perfluoroalkoxy alkane) Exposed surface ~ 7cm²



Silicon Exposed surface ~5cm²







Method validation

Accumulation rate on PFA and Si surfaces



Class 10000 clean room at PNNL, 29 day exposure



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Source: https://pubs.usgs.gov/of/2005/1413/maps.htm



Room air – Class 10000 clean room comparison



PFA surface, 30 day exposure









Pacific







SNO+ detector



The acrylic vessel



Th & U accumulation from mine dust: Estimated* (Fe, XRF) vs measured (ICP-MS)

*SNOLAB-STR-2007-003 Fe/Th = 1.1E+4Fe/U = 4.9E+4

A: Mezzanine at LBL on desk

E: SNO+ control room

F: Dirty side of the carwash



B: Close to dust monitor in SCDMS area C: Hallway close to PICO @ 2.5m



- U (estimated)
- Th (ICP-MS)
- U (ICP-MS)



B: Close to dust monitor in SCDMS area C: Hallway close to PICO @ 2.5m

> Th (estimated) U (estimated) Th (ICP-MS) U (ICP-MS)



*SNOLAB-STR-2007-003 Fe/K = 6.56 (rock)



A: Mezzanine at LBL on desk B: Close to dust monitor in SCDMS area C: Hallway close to PICO @ E: SNO+ control room F: Dirty side of the carwash



K accumulation from concrete: Estimated* (Ca, XRF) vs measured (ICP-MS)

*SNOLAB-STR-2007-003 Ca/K = 6.27 (concrete)



A: Mezzanine at LBL on desk B: Close to dust monitor in SCDMS area C: Hallway close to PICO @

E: SNO+ control room F: Dirty side of the carwash





Dust contribution to surface contamination

- > Limiting
- Inferred, estimated, assumed

> ICP-MS

- Rapid, direct identification and quantitation
- Ultra sensitive
- Bulk + surface analysis

First direct measurement of deposition rate of contamination from dust

- Actual direct measurement not matching predictions
- Informing backgrounds



SCDMS detector components







MAJORANA DEMONSTRATOR detector components



How can we support ULB detectors?

Contribution to contamination from exposure to dust (even in clean rooms!)

- First direct measurement
- > Qualitative and quantitative

Study of contribution in significant locations

Valuable for planning detector assembly and installation

Study of contribution variation with ongoing activities

Measurement not limited to K Pb Th U!

- ICP-MS potential analysis of almost all the periodic table
- > Forensic: identification of the contamination source
- > Finger print of unwanted contamination carriers





Thank you

Sonia Alcantar Khadouja Harouaka DOE Detector R&D for High Energy Physics (KA-25)



BACK UP SLIDES

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From SNOLAB-STR-2007-003

Element	Detection Limit	Rock Sample 8	Rock Sample 11	Shotcrete Sample 15	Concrete Sample 14
	(ppm)	(ppm)	(ppm)	(ppm)	(ppm)
Th	0.02	5.54	5.19	14.9	13.1
U	0.005	1.21	1.14	2.56	2.38

Table 2: The ICP-MS results for each measured element in ppm. Note that N.D. is used if the element was not detected.

Element	Detection Limit	Rock Sample 8	Rock Sample 11	Shotcrete
	(ppm)	(%)	(%)	(%)
Al	100	6.01	6.43	6.04
Ca	90	3.43	3.80	9.54
Fe	200	6.37	6.68	2.54
K	30	0.97	1.02	1.76

Table 3: The ICP-AES results for Al, Ca, Fe, K, Mg, Mn and Na. The WD-XRF results for silicon and the gamma-ray spectroscopy results for H, C and O.







5.52E(-05)





1.57E(-09)

* Nat Pb activity from A.Alessandrello et al./Nucl. Instr. And Meth. In Phys. Res. B 142 (1998) 163-172









U [μBq day⁻¹ cm⁻²]





Exposure of a Si wafer



Si wafer Surface ~ 700 cm² Thickness 0.77 mm Density 2.33 g cm⁻³



https://www.svmi.com/silicon-wafers/300mm-wafers/





Contamination after a month exposure of the Si wafer in SNOLAB locations normalized to the total wafer mass

		Th		U
		[ppt/month/wafer]	sd	[pp
A	Mezzanine at LBL on desk	2.04E-02	7.78E-03	
В	Close to the dust monitor in SCDMS area	1.37E-01	1.10E-01	
С	Hallway close to PICO @ 2.5m	1.77E-02	1.31E-02	
D	Bottom of cryopit (quiet area) on desk	5.46E-03	8.21E-03	
Е	SNO+ control room	3.20E-02	1.09E-02	
F	Dirty side of the carwash	1.39E+01	2.16E+00	
G	Close to dust monitor in Juntion carwash-Refuge-OldLab	3.49E-01	2.10E-02	
Н	Surface building @ 3rd floor	1.32E+01	4.92E+00	
I	Hallway J Drift @ 2.5m	2.10E-01	8.21E-02	
J	Chem Lab on top of cabinet	2.44E+00	1.57E+00	
K	Top of the stairs entering the DEAP area	9.36E-02	4.35E-02	

pt/month/wafer] sd 1.97E-02 4.58E-03 8.60E-02 4.29E-02 6.88E-03 1.19E-02 7.77E-03 8.99E-03 4.99E-02 1.51E-02 8.33E+00 1.90E+00 1.94E-01 4.31E-02 2.67E+00 1.89E-01 1.95E-02 1.30E-02 6.04E-01 3.72E-01 2.10E-02 9.53E-03